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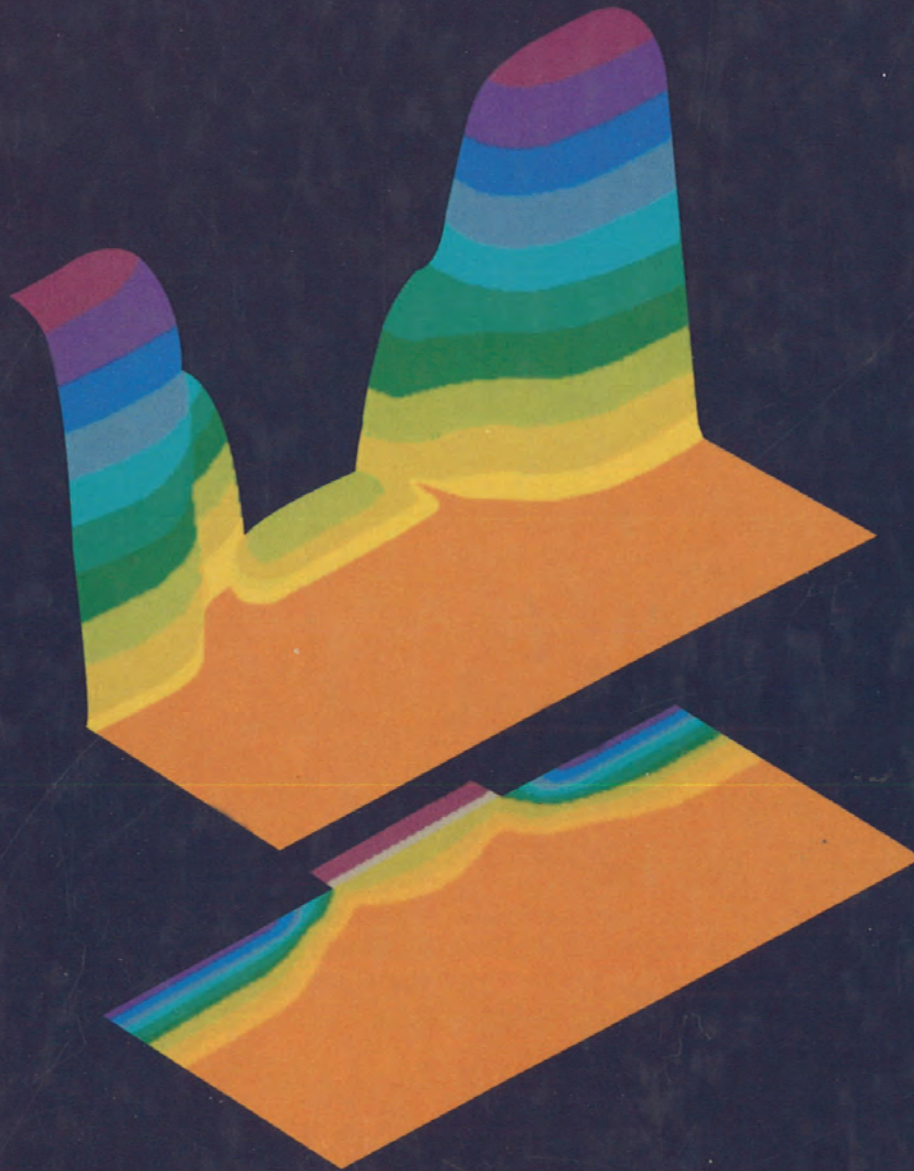
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# EXHIBIT A

# Silicon Processing

for the VLSI Era

Volume 3 - The Submicron MOSFET



S. Wolf

THE COMPANION VOLUMES TO THIS BOOK

## Silicon Processing for the VLSI Era

Volume 1 - Process Technology

By STANLEY WOLF and RICHARD N. TAUBER

**TABLE of CONTENTS** - Ch. 1 Silicon: Single-Crystal Growth and Waterring; Ch. 2 Crystalline Defects, Thermal Processing, and Gettering; Ch. 3 Vacuum Technology for VLSI Applications; Ch. 4 Basics of Thin Films; Ch. 5 Silicon Epitaxial Film Growth; Ch. 6 Chemical Vapor Deposition of Amorphous and Polycrystalline Films; Ch. 7 Thermal Oxidation of Silicon; Ch. 8 Diffusion in Silicon; Ch. 9 Ion Implantation for VLSI; Ch. 10 Aluminum Thin Films and Physical Vapor Deposition in VLSI; Ch. 11 Refractory Metals and Their Silicides in VLSI; Ch. 12 Lithography I: Optical Photoresists - Material Properties and Process Technology; Ch. 13 Lithography II: Optical Aligners and Photomasks; Ch. 14 Advanced Lithography: E-Beam and X-Ray; Ch. 15 Wet Processing: Cleaning, Etching, and Lift-Off; Ch. 16 Dry Etching for VLSI; Ch. 17 Material Characterization Techniques for VLSI Fabrication; Ch. 18 Structured Approach to Design of Experiments for Process Optimization.

1986 LATTICE PRESS 660 pp. ISBN 0-9616721-3-7

Volume 2 - Process Integration

By STANLEY WOLF

**TABLE of CONTENTS** - Ch. 1 Process Integration for VLSI and ULSI; Ch. 2 Isolation Technologies for Integrated Circuits; Ch. 3 Contact Technology and Local Interconnects for VLSI; Ch. 4 Multilevel Interconnect Technology for VLSI and ULSI; Ch. 5 NMOS Devices and Process Integration; Ch. 6 CMOS Process Integration; Ch. 7 Bipolar and BiCMOS Process Integration; Ch. 8 Semiconductor Memory Process Integration; Ch. 9 Process Simulation.

1990 LATTICE PRESS 752 pp. ISBN 0-9616721-4-5

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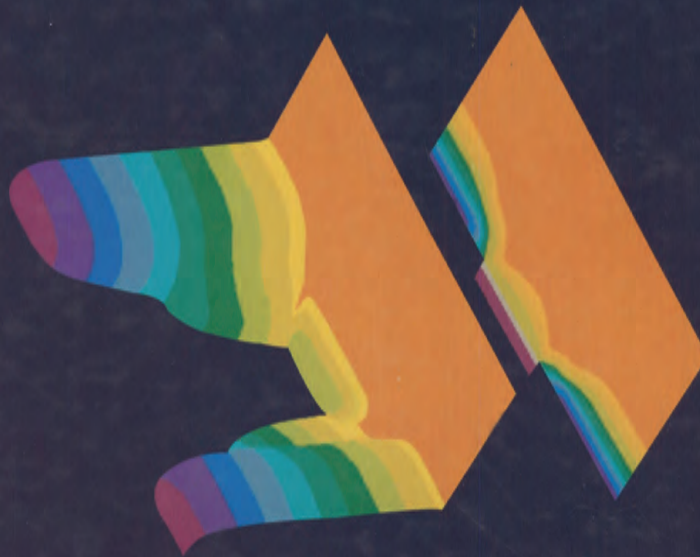
Volume 3

The  
Submicron  
MOSFET

S. Wolf

TK  
7874  
W635  
1986  
v.3

## Silicon Processing for the VLSI Era Volume 3 - The Submicron MOSFET



S. Wolf

**SILICON PROCESSING  
FOR  
THE VLSI ERA**

**VOLUME 3:  
THE SUBMICRON MOSFET**

**STANLEY WOLF Ph.D.**  
Professor, Department of Electrical Engineering  
California State University, Long Beach  
Long Beach, California

**LATTICE PRESS**

Sunset Beach, California

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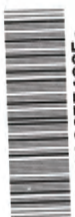
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1

Material type

Book

Item policy

general (book)

Provenance

-

Is magnetic

No

PO Line

Issue date

-

Receiving date

02/12/2002

Expected receiving date

-

Enumeration A

3

Enumeration B

-

Chronology I

-

Chronology J

-

Description

3

Pages

-

Pieces

1

Replacement cost

-

Receiving operator

import

Physical condition

-

Process type

Inventory Information

Inventory number

ONSEMI EXHIBIT 1015, Page 11

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Page 11

|                 |   |
|-----------------|---|
|                 | - |
| Inventory date  | - |
| Inventory price | - |

Location Information

|                       |                                           |
|-----------------------|-------------------------------------------|
| Permanent location    | Steenbock Library: Steenbock Stacks (stk) |
| Item call number type | -                                         |
| Item call number      | -                                         |
| Source (Subfield 2)   | -                                         |
| Storage location ID   | -                                         |

Temporary Location Information

|                               |    |
|-------------------------------|----|
| Item is in temporary location | No |
| Temporary location            | -  |
| Temporary call number type    | -  |
| Temporary call number         | -  |
| Temporary source (Subfield 2) | -  |
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# EXHIBIT A



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THE VLSI ERA**

**VOLUME 4:  
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**STANLEY WOLF Ph.D.**

**LATTICE PRESS  
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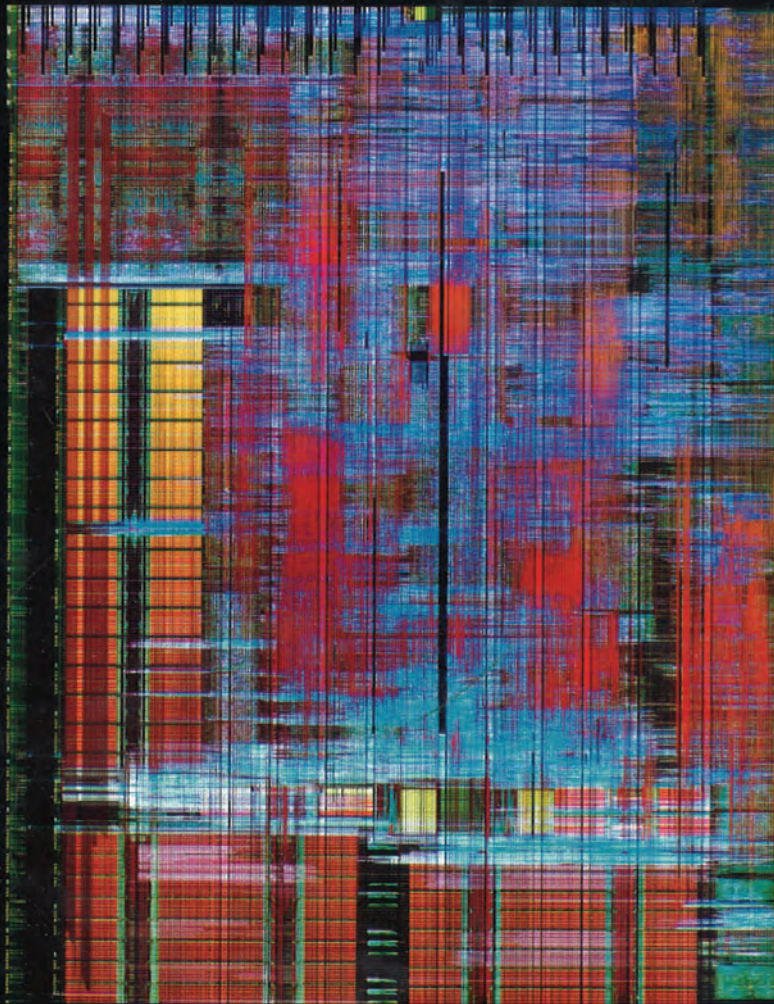
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FIFTH EDITION

# SOLID STATE ELECTRONIC DEVICES



**BEN G. STREETMAN ■ SANJAY BANERJEE**

Prentice Hall Series in Solid State Physical Electronics, Nick Holonyak, Jr., Series Editor

This is the fifth edition of the most widely used introductory book on semiconductor materials, physics, devices and technology. Previous editions have been translated into English and Polish. The book was written with two basic goals in mind: 1) develop the physics concepts to understand current and future devices; 2) provide a source of current semiconductor devices and technology so that their applications in optoelectronic circuits and systems can be appreciated.

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- incorporates the basics of semiconductor materials and conduction processes in solids needed to understand p-n junctions, bipolar and metal oxide semiconductor (MOS) transistors, optoelectronic and other devices.
- greatly expanded and updated discussion of device fabrication processes and CMOS integrated circuit technology, along with new data in the Appendices, provides a useful understanding of how semiconductor devices are made.
- extensive discussion of circuit and other application examples to provide students with feedback about the practical relevance of the theory.
- completely updated discussion of MOS devices, both in the underlying theory as well as discussion of short channel, high field and hot carrier effects in scaled MOSFETs, recognizing the current preponderance of CMOS.
- updated, consolidated treatment of optoelectronic devices, including sources such as blue GaN-based LEDs and semiconductor vertical-cavity surface-emitting lasers, as well as detectors such as avalanche and resonant-cavity photodiodes.
- includes a listing of the key equations for semiconductor devices on the inside covers of the book, arranged thematically to help students digest the concepts.
- about 200 problems and current references which extend concepts in the text.



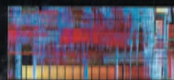
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**SANJAY BANERJEE** is the Cullen Trust Endowed Professor of Electrical and Computer Engineering, and Director of the Microelectronics Research Center at The University of Texas at Austin. He has more than 225 archival refereed publications and 12 U.S. patents, and has supervised 18 Ph.D. students. His honors include the NSF Presidential Young Investigator Award (1988), the Texas Atomic Energy Centennial Fellowship (1990-1997), Distinguished National Lecturer for the IEEE Electron Devices Society (1997-), and Fellow of the IEEE (1993).

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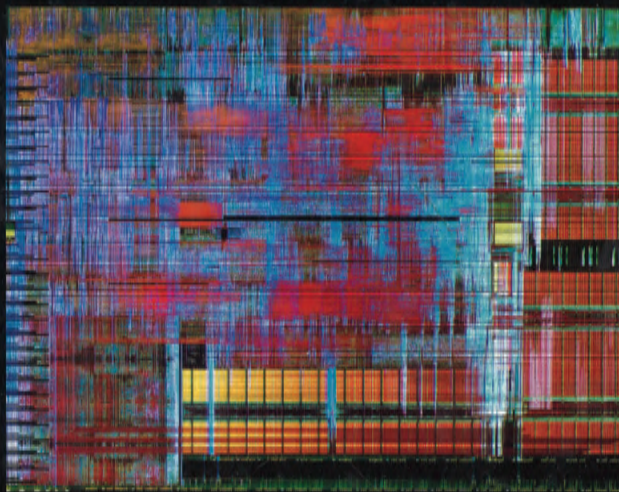


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#### KEY FEATURES:

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- greatly expanded and updated discussion of device fabrication processes and CMOS integrated circuit technology, along with new data in the Appendices, provides a useful understanding of how semiconductor devices are made.
- extensive discussion of circuit and other application examples to provide students with feedback about the practical relevance of the theory.
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# Solid State Electronic Devices

**BEN G. STREETMAN AND SANJAY BANERJEE**

*Microelectronics Research Center  
Department of Electrical and Computer Engineering  
The University of Texas at Austin*



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**General Library System**  
**University of Wisconsin - Madison**  
**728 State Street**  
**Madison, WI 53706-1494**  
**U.S.A.**

# EXHIBIT B



Resource description

[Solid state electronic devices / Ben G. Streetman and Sanjay Banerjee. Streetman, Ben G. Prentice Hall, Upper Saddle River, N.J. : 2000 \[0130255386 \(casebound\)\]](#)

Holdings

[Steenbock Library: Steenbock Stacks; TK7871.85 S77 2000 2](#)

Holdings ID

22859343910002122

Barcode

89081141418

Item ID

23637120370002122

Process type

[Loan](#)

MMS ID

9953213393602122

Status

[Browse shelf listing](#)

Item not in place

General

ENUM/CHRON

Notes

History

General Information

Barcode

89081141418

Copy ID

2

Material type

Book

Item policy

general (book)

Provenance

Is magnetic

No

PO Line

Issue date

Receiving date

01/22/2004

Expected receiving date

Enumeration A

Enumeration B

Chronology I

Chronology J

Description

Generate

Pages

Pieces

1

Replacement cost

Receiving operator

import

Physical condition

Process type

Inventory Information

Inventory number

Inventory date

Inventory price

Clear Inventory Information

Location Information

Permanent location \*

Steenbock Library: Steenbock Stacks (stk)

Item call number type

Item call number

Source (Subfield 2)

Storage location ID

Temporary Location Information

Item is in temporary location

No

☐

Yes

☐

Temporary location

Temporary call number type

Temporary call number

Temporary source (Subfield 2)

Temporary item policy

Due back date

Retention Information

Committed to Retain

☐

No

☐

Yes

Retention Reason

Retention Note